## PATENT ASSIGNMENT COVER SHEET

Electronic Version v1.1 Stylesheet Version v1.2 EPAS ID: PAT6689254

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	CONFIRMATION OF FORECLOSURE TRANSFER OF PATENT RIGHTS

### **CONVEYING PARTY DATA**

Name	Execution Date
UTICA LEASECO, LLC SECURED PARTY	02/25/2021

### **RECEIVING PARTY DATA**

Name:	UTICA LEASECO, LLC ASSIGNEE									
Street Address:	905 SOUTH BOULEVARD EAST									
City:	ROCHESTER									
State/Country:	MICHIGAN									
Postal Code:	48307									

### **PROPERTY NUMBERS Total: 1**

Property Type	Number
Application Number:	15422218

### **CORRESPONDENCE DATA**

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Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent

using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.

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ATTORNEY DOCKET NUMBER:	041223.00342
NAME OF SUBMITTER:	SCOTT DODGE
SIGNATURE:	/Scott Dodge/
DATE SIGNED:	05/03/2021

### **Total Attachments: 32**

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# Confirmation of Foreclosure Transfer of Patent Rights

This Confirmation of Foreclosure Transfer of Patent Rights (this Confirmation) is dated February 25, 2021 and is executed by Utica Leaseco, LLC, a Florida limited liability company (the Secured Party).

Pursuant to a Master Lease Agreement dated February 6, 2017, and an Equipment Schedule ALTA-0002 dated April 25, 2019, the Secured Party extended credit to Alta Devices, Inc., a Delaware corporation (the Debtor). As security for the credit extended by the Secured Party to the Debtor, the Debtor granted to the Secured Party a security interest under the Uniform Commercial Code in collateral including the following intellectual property and patents (the Patent Collateral):

- Each patent and patent application listed in <u>Schedule A</u> attached hereto. (a)
- All reissues, substitutes, divisions, continuations, continuations-in-part, extensions, renewals, reexaminations, counterpart foreign applications, and any other applications claiming priority in the patent and patent application listed in Schedule A attached hereto.
- All inventions and improvements described and claimed therein. (c)

The Debtor executed a Confirmation of Security Agreement on April 25, 2019; that Confirmation was recorded with the USPTO on April 29, 2019, at Reel 049027, Frame 0944.

The Debtor defaulted in the payment and performance of the obligations secured by the Patent Collateral, whereupon the Secured Party, in the exercise of its rights as a secured party under the Uniform Commercial Code, gave notice to the Debtor that the Secured Party would conduct a public foreclosure sale of the Patent Collateral. The Secured Party gave notice to the Debtor of the planned foreclosure sale on February 21, 2020 by certified mail, return receipt requested. The Secured Party also sent that notice to Hanergy Thin Film Power Group Limited and all other parties entitled to such notice under Section 9-611 of the Uniform Commercial Code.

The Secured Party conducted the foreclosure sale on Tuesday, March 3, 2020, at 9:15 a.m., at 660 Woodward Avenue, Detroit, Michigan 48226. At the foreclosure sale, the Secured Party (in this capacity, the Assignee) was the highest bidder for the Patent Collateral, bidding the sum of \$33,400,000.00 for the Patent Collateral. As a result, the Secured Party, pursuant to Section 9-617(a) of the Uniform Commercial Code, transferred to the Assignee all of the rights of the Debtor in and to the Patent Collateral.

Therefore, this Confirmation confirms that the Assignee has become the owner, free and clear of all liens, security interests, and adverse claims, of all of the Patent Collateral.

In witness whereof, the Secured Party and the Assignee have executed this Confirmation as of the date first written above.

Secured Party

Utica Leaseco, LLC

Assignee

Utica Leaseco, LLC

# SCHEDULE A

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Granted	Abandoned	Abandoned	Abandoned	Abandoned	Abandoned	Abandoned	Closed	Abandoned	Abandoned	Granted	Abandoned	Expired	Abandoned	Abandoned	Abandoned	Closed	Granted	Granted	Abandoned	Expired	Abandoned	Sights

Granted	EPITAXIAL LIFT OFF STACK HAVING A PRE-	06/30/2015	9,070,764 B2	05/29/2009	12/475406	SN
Abandoned	MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF			10/12/2009	10-2011-7010493	KR
Granted	EPITAXIAL LIFT OFF STACKS AND METHODS	08/31/2015	10-1550480	05/29/2009	10-2010-7029634	KR
Abandoned	EPITAXIAL LIFT OFF STACKS AND METHODS			05/29/2009	2011-511866	JP
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Abandoned	MESA ETCH METHOD AND COMPOSITION			10/12/2009	09820035.5	EP
Abandoned	EPITAXIAL LIFT OFF STACKS AND METHODS			05/29/2009	09767433.7	ΕP
Granted	CURVED HANDLE AND METHODS THEREOF	06/13/201/	9,6/9,814 B2	05/2//2015	14//23223	US
Closed	MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF	·		10/12/2009	200980140141.0	CN
Abandoned	EPITAXIAL LIFT OFF STACKS AND METHODS			05/29/2009	200980126340.6	Ŧ
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Abandoned	MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF			10/12/2009	2,739,327	CA
Abandoned	CONCENTRIC SHOWERHEAD FOR VAPOR DEPOSITION			10/09/2009	98134405	TW
Granted	METHODS AND APPARATUS FOR A CHEMICAL VAPOR DEPOSITION REACTOR	03/11/2015	1476295	06/01/2009	098118062	™
Expired	LEVITATING SUBSTATE CARRIER			12/15/2008	61/122591	SN
Expired	METHOD AND APPARATUS FOR A CHEMICAL VAPOR DEPOSITION REACTOR			10/10/2008	61/104284	SN
Expired	METHOD AND APPARATUS FOR A CHEMICAL VAPOR DEPOSITION REACTOR			10/10/2008	61/104283	SN
Expired	METHOD AND APPARATUS FOR A CHEMICAL VAPOR DEPOSITION REACTOR	<b></b>		05/30/2008	61/057788	Sn
Expired	CONCENTRIC SHOWERHEAD FOR VAPOR DEPOSITION			10/09/2009	PCT/US2009/060260	PC
Closed	AND APPARA POR DEPOSIT			05/29/2009	PCT/US2009/045709	PC
Granted	CONCENTRIC SHOWERHEAD FOR VAPOR DEPOSITION	09/01/2015	9,121,096 B2	10/09/2009	12/576797	SN

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08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF  11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  05/06/2014 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  02/05/2013 EPITAXIAL LIFT OFF STACK HAVING A MULTI- LAYERED HANDLE AND METHODS THEREOF  06/23/2015 MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF STACKS AND METHODS  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  EPITAXIAL LIFT OFF STACKS AND METHODS  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  EPITAXIAL LIFT OFF STACKS AND METHODS  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  EPITAXIAL LIFT OFF STACKS AND METHODS  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  EPITAXIAL LIFT OFF STACKS AND METHODS  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF	10326033 B2	02/20/2013	13/772043	SN
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF  11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  05/06/2014 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  02/05/2013 EPITAXIAL LIFT OFF STACK HAVING A MULTI- LAYERED HANDLE AND METHODS THEREOF  06/23/2015 MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF STACKS AND METHODS  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF EPITAXIAL LIFT OFF STACKS AND METHODS		10/12/2009	98134512	TW
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF  11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  05/06/2014 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  02/05/2013 EPITAXIAL LIFT OFF STACK HAVING A MULTI- LAYERED HANDLE AND METHODS THEREOF  06/23/2015 MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  EPITAXIAL LIFT OFF STACKS AND METHODS  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  EPITAXIAL LIFT OFF STACKS AND METHODS  EPITAXIAL LIFT OFF STACKS AND METHODS  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  EPITAXIAL LIFT OFF STACKS AND METHODS  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF		06/01/2009	98118055	₩
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF  11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  05/06/2014 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  02/05/2013 EPITAXIAL LIFT OFF STACK HAVING A MULTI- LAYERED HANDLE AND METHODS THEREOF  06/23/2015 MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  EPITAXIAL LIFT OFF STACKS AND METHODS  EPITAXIAL LIFT OFF STACKS AND METHODS  EPITAXIAL LIFT OFF STACKS AND METHODS		10/10/2008	61/104287	SN
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF  11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  05/06/2014 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  02/05/2013 EPITAXIAL LIFT OFF STACK HAVING A MULTI- LAYERED HANDLE AND METHODS THEREOF  06/23/2015 MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF STACKS AND METHODS  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF EPITAXIAL LIFT OFF STACKS AND METHODS  EPITAXIAL LIFT OFF STACKS AND METHODS  EPITAXIAL LIFT OFF STACKS AND METHODS		10/10/2008	61/104286	SN
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF  11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  05/06/2014 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  02/05/2013 EPITAXIAL LIFT OFF STACK HAVING A MULTI- LAYERED HANDLE AND METHODS THEREOF  06/23/2015 MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF	,,,,,,,,	05/30/2008	61/057784	SN
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF  11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  05/06/2014 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  02/05/2013 EPITAXIAL LIFT OFF STACK HAVING A MULTI- LAYERED HANDLE AND METHODS THEREOF  06/23/2015 MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF  EPITAXIAL LIFT OFF STACKS AND METHODS  EPITAXIAL LIFT OFF STACKS AND METHODS		10/12/2009	PCT/US2009/060382	PC
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF  11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  05/06/2014 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  02/05/2013 EPITAXIAL LIFT OFF STACK HAVING A MULTI-  02/05/2013 EPITAXIAL LIFT OFF STACK HAVING A MULTI- LAYERED HANDLE AND METHODS THEREOF  06/23/2015 MESA ETCH METHOD AND COMPOSITION FOR EPITAXIAL LIFT OFF		05/29/2009	PCT/US2009/045715	PC
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF  11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  05/06/2014 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  02/05/2013 EPITAXIAL LIFT OFF STACK HAVING A MULTI- LAYERED HANDLE AND METHODS THEREOF	9,064,810 B2	10/12/2009	12/577645	SN
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF  11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF  05/06/2014 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF	8,367,518 B2	05/29/2009	12/475420	SO
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF 11/20/2012 EPITAXIAL LIFT OFF STACK HAVING A NON- UNIFORM HANDLE AND METHODS THEREOF	8,/16,10/62	06/28/2012	13/536043	US
08/23/2011 EPITAXIAL LIFT OFF STACK HAVING A UNIDIRECTIONALLY SHRUNK HANDLE AND METHODS THEREOF	8,314,011 B2	05/29/2009	12/475418	SO
	8,003,492 B2	05/29/2009	12/475415	Sn
11/13/2012	8,309,432 B2	05/29/2009	12/475411	Sn

Expired	PHOTOVOLTAIC DEVICE WITH BACK SIDE CONTACTS			10/23/2009	PCT/US2009/061914	PC
Granted		05/12/2015	9,029,687 B2	10/23/2009	12/605151	SN
Abandoned	PHOTOVOLTAIC DEVICE WITH BACK SIDE CONTACTS			10/23/2009	10-2011-7011463	KR
Closed	C DEVICE W			10/23/2009	09822800.0	EP
Pending	C DEVICE CONTACT	,,,,,,,,,		10/23/2009	200980151530.3	CN
Granted	PHOTOVOLTAIC DEVICE WITH BACK SIDE CONTACTS	10/06/2020	10797187B2	05/07/2015	14/706704	Sn
Closed	PHOTOVOLTAIC DEVICE WITH INCREASED LIGHT TRAPPING	,,,,,,,,,			098136016	TW
Expired	PHOTOVOLTAIC DEVICE WITH INCREASED LIGHT TRAPPING	,,,,,,,,		10/23/2008	61/107962	Sn
Expired	PHOTOVOLTAIC DEVICE WITH INCREASED LIGHT TRAPPING			10/23/2009	PCT/US2009/061911	РС
Granted	PHOTOVOLTAIC DEVICE WITH INCREASED LIGHT TRAPPING	04/01/2014	8,686,284 B2	10/23/2009	12/605140	Sn
Granted	PHOTOVOLTAIC DEVICE WITH INCREASED LIGHT TRAPPING	11/25/2014	8,895,847 B2	11/05/2010	12/940966	Sn
Abandoned	THIN ABSORBER LAYER OF A PHOTOVOLTAIC DEVICE	,,,,,,,,,		10/23/2009	098136006	WT
Expired		,,,,,,,,		10/23/2008	61/107959	Sn
Expired	LAYER OF			10/23/2009	PCT/US2009/061906	РС
Granted	THIN ABSORBER LAYER OF A PHOTOVOLTAIC DEVICE	03/18/2014	8,674,214 B2	10/23/2009	12/605129	Sn
Closed	THIN ABSORBER LAYER OF A PHOTOVOLTAIC DEVICE	,,,,,,,,		10/23/2009	10-2011-7011461	KR
Closed	THIN ABSORBER LAYER OF A PHOTOVOLTAIC DEVICE			10/23/2009	09822796.0	EP
Granted	PHOTOVOLTAIC DEVICE INCLUDING AN INTERMEDIATE LAYER	12/16/2014	8,912,432 B2	11/05/2010	12/940955	Sn
Granted	THIN ABSORBER LAYER OF A PHOTOVOLTAIC DEVICE	03/11/2014	8,669,467 B2	11/05/2010	12/940918	SN

09/05/2014 TILED SUBSTRATES FOR DEPOSITION AND EPITAXIAL LIFT OFF PROCESSES
TILED SUBSTRATES FOR DEPOSITION AND EPITAXIAL LIFT OFF PROCESSES
04/20/2016 TILED SUBSTRATES FOR DEPOSITION AND EPITAXIAL LIFT OFF PROCESSES
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Abandoned	/STEM AND			12/12/2011	13/257264	SN
Abandoned	VAPOR DEPOSITION REACTOR SYSTEM AND METHODS THEREOF	,,,,,,,,,		03/16/2010	10-2011-7024339	Ŕ
Abandoned	ION REACTOR S			03/16/2010	2012-500902	JP
Abandoned	VAPOR DEPOSITION REACTOR SYSTEM AND METHODS THEREOF			03/16/2010	10754006.4	EP
Abandoned	VAPOR DEPOSITION REACTOR SYSTEM AND METHODS THEREOF			03/16/2010	201510196727.6	CN
Granted	VAPOR DEPOSITION REACTOR SYSTEM AND METHODS THEREOF	05/13/2015	201080020505.4	03/16/2010	201080020505.4	CN
Abandoned	STACK DEPOSIT TAXIAL LIFT OF	,,,,,,,,,,		12/08/2009	98141933	WT
Expired	MULTIPLE STACK DEPOSITION FOR EPITAXIAL LIFT OFF			12/07/2009	PCT/US2009/067027	PC
Granted	MULTIPLE STACK DEPOSITION FOR EPITAXIAL LIFT OFF	06/30/2015	9,068,278 B2	12/07/2009	12/632565	Sn
Expired	TACK DEPOSIT AXIAL LIFT OFI	,,,,,,,,,,		12/08/2008	61/120687	Sn
Abandoned	MULTIPLE STACK DEPOSITION FOR EPITAXIAL LIFT OFF			12/07/2009	10-2011-7015616	KR
Abandoned	TACK DEPOSI TAXIAL LIFT OI			12/07/2009	09836686.7	EP
Abandoned	MULTIPLE STACK DEPOSITION FOR EPITAXIAL LIFT OFF			12/07/2009	200980155968.9	CN
Abandoned	TILED SUBSTRATES FOR DEPOSITION AND EPITAXIAL LIFT OFF PROCESSES			03/01/2010	99105856	WT
Granted	TILED SUBSTRATES FOR DEPOSITION AND EPITAXIAL LIFT OFF PROCESSES	01/29/2013	8,362,592 B2	03/01/2010	12/715243	Sn
Expired	TILED SUBSTRATES FOR DEPOSITION AND EPITAXIAL LIFT OFF PROCESSES			03/01/2010	PCT/US2010/025796	PC
Expired	TILED SUBSTRATES FOR DEPOSITION AND EPITAXIAL LIFT OFF PROCESSES			02/27/2009	61/156404	Sn
Abandoned	TILED SUBSTRATES FOR DEPOSITION AND EPITAXIAL LIFT OFF PROCESSES	,,,,,,,,,,		03/01/2010	10-2011-7022442	KR
Granted	TILED SUBSTRATES FOR DEPOSITION AND EPITAXIAL LIFT OFF PROCESSES	07/08/2016	5963213	03/01/2010	2014-110180	JP

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10754014.8	201080021046.1	99107657	PCT/US2010/027545	12/725326	10-2011-7024340	2012-500906	10754013.0	201080021014.1	9910/644		DCT /I ISON10/0375/3	13/257273		10-2011-7024338	2012-500905	10/54010.6	1015 1010 6	201080020750.5	99107650	PCT/US2010/027540	13/257269	10-2011-7024341	2012-500904	10754008.0	201080020492.0	99107659	PCT/US2010/027538
03/16/2010	03/16/2010	03/16/2010	03/16/2010	03/16/2010	03/16/2010	03/16/2010	03/16/2010	03/16/2010	03/16/2010	00/10/2010	02/16/2010	11/23/2011		03/16/2010	03/16/2010	03/16/2010	02/16/2010	03/16/2010	03/16/2010	03/16/2010	12/12/2011	03/16/2010	03/16/2010	03/16/2010	03/16/2010	03/16/2010	03/16/2010
	ZL201080021046.1						,,,,,,											ZL 201080020750.5			8,985,911 B2				ZL201080020492.0		
	10/14/2015						,,,,,,											08/31/2016			03/24/2015			,,,,,,	10/15/2014	,,,,,,,,,,	
REACTOR LID ASSEMBLY FOR VAPOR DEPOSITION	REACTOR LID ASSEMBLY FOR VAPOR DEPOSITION	SHOWERHEAD FOR VAPOR DEPOSITION	HEATING LAMP SYSTEM AND METHODS THEREOF	THEREOF	HEATING I AND SYSTEM AND METHODS	HEATING LAMP SYSTEM AND METHODS THEREOF	THEREOF	HEATING LAMP SYSTEM AND METHODS	HEATING LAMP SYSTEM AND METHODS THEREOF	THEREOF	THEREOF	HEATING LAMP SYSTEM AND METHODS	WAFER CARRIER TRACK	VAPOR DEPOSITION REACTOR SYSTEM AND METHODS THEREOF	VAPOR DEPOSITION REACTOR SYSTEM AND METHODS THEREOF												
Abandoned	Granted	Abandoned	Expired	Abandoned	Abandoned	Abandoned	Abandoned	Abandoned	Abandoned	rypiica	Evpired	Abandoned		Abandoned	Abandoned	Abaridoried	All	Granted	Abandoned	Expired	Granted	Abandoned	Abandoned	Abandoned	Granted	Abandoned	Expired

Granted	REACTOR CLEAN	09/08/2015	9,127,364 B2	10/27/2010	12/913688	SN
	TEXTURED METALLIC BACK REFLECTORS	,,,,,,			99135011	™
	TEXTURED METAL-DIELECTRIC BACK REFLECTORS			10/14/2009	61/251684	SN
	TEXTURED METALLIC BACK REFLECTORS			10/14/2009	61/251681	SN
	TEXTURED METALLIC BACK REFLECTORS			10/14/2010	PCT/US2010/052706	PC
	TEXTURED METALLIC BACK REFLECTOR	06/27/2017	9,691,921 B2	10/13/2010	12/904047	US
	TEXTURED METALLIC BACK REFLECTOR	03/16/2017	10-1719020	10/14/2010	10-2012-7012346	KR
	TEXTURED METALLIC BACK REFLECTORS			10/14/2010	2012-534363	JP
	TEXTURED METALLIC BACK REFLECTOR	09/16/2015	ZL201080046469.9	10/14/2010	201080046469.9	CN
Abandoned	TAP-BASED EPITAXIAL LIFT OFF APPARATUSES AND METHODS			12/17/2009	98143360	™
	HANDLING METHODS AND APPARATUS					
	TAPE-BASED EPITAXIAL LIFT OFF AND			11/02/2009	61/257326	SN
	METHODS					
	EPITAXIAL LIFT OFF APPARATUS AND			12/17/2008	61/138440	SN
	TAP-BASED EPITAXIAL LIFT OFF APPARATUSES AND METHODS			12/17/2009	PCT/US2009/068445	PC
	APPARATUSES AND METHODS		·	٠		
	TAPE-BASED EPITAXIAL LIFT OFF	10/20/2015	9,165,805	12/17/2009	12/640796	SU
Abandoned	TAP-BASED EPITAXIAL LIFT OFF APPARATUSES AND METHODS			12/17/2009	10-2011-7016546	Ŕ
	APPARATUSES AND METHODS					
	TAPE-BASED EPITAXIAL LIFT OFF	05/29/2019	2359393	12/17/2009	09836939.0	EP
	TAPE-BASED EPITAXIAL LIFT OFF APPARATUSES AND METHODS			12/17/2009	200980155618.2	2
***************************************	DEPOSITION					
Abandoned	REACTOR LID ASSEMBLY FOR VAPOR			03/16/2010	99107646	WT
	DEPOSITION					
	REACTOR LID ASSEMBLY FOR VAPOR			03/16/2010	PCT/US2010/027547	PC
Abandoned	REACTOR LID ASSEMBLY FOR VAPOR DEPOSITION			11/23/2011	13/257275	SN
	DEPOSITION					
	REACTOR LID ASSEMBLY FOR VAPOR	09/04/2013		03/16/2010	10-2011-7024337	KR
	REACTOR LID ASSEMBLY FOR VAPOR DEPOSITION			03/16/2010	2012-500907	JР
	4	,			,	

	GROUP III/V MATERIALS					
Granted	HIGH GROWTH RATE DEPOSITION FOR	10/21/2015	ZL 201080046939.1	10/14/2010	201080046939.1	CN
Abandoned	HIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS	,,,,,,,,,,		10/14/2010	2777544	CA
Abandoned	RUCTURES FO NCLUDING OP NPPARATUSES			01/24/2011	201180015400.4	CN
Expired	SUPPORT STRUCTURES FOR VARIOUS APPARATUSES INCLUDING OPTO-ELECTRICAL APPARATUSES			01/24/2011	PCT/US2011/022300	PC
Abandoned	SUPPORT STRUCTURES FOR VARIOUS APPARATUSES INCLUDING OPTO-ELECTRICAL APPARATUSES			01/24/2011	100102541	WT
Expired	METHODS FOR FORMING EPITAXIAL LIFT OFF STACKS CONTAINING LAMINATED METALLIC SUPPORT FILMS			01/22/2010	61/297702	Sn
Expired	LAMINATED METALLIC SUPPORT FILMS FOR EPITAXIAL LIFT OFF STACKS	,,,,,,,,,,		01/22/2010	61/297692	Sn
Abandoned	SUPPORT STRUCTURES FOR VARIOUS APPARATUSES INCLUDING OPTO-ELECTRICAL APPARATUSES			01/24/2011	13/012741	Sn
Expired	SUPPORT STRUCTURES FOR VARIOUS APPARATUSES INCLUDING OPTO-ELECTRICAL APPARATUSES			01/24/2011	PCT/US2011/022296	PC
Pending	MIXED WIRING SCHEMES FOR SHADING ROBUSTNESS			09/22/2011	100134183	WT
Expired	MIXED WIRING SCHEME FOR SHADING ROBUSTNESS	,,,,,,,,,,		09/25/2009	61/245907	Sn
Abandoned	MIXED WIRING SCHEME FOR SHADING ROBUSTNESS			09/24/2010	12/890368	SN
Granted	MIXED WIRING SCHEME FOR SHADING ROBUSTNESS	12/10/2012	10-1212868	09/23/2011	10-2011-0096513	KR
Pending	MIXED WIRING SCHEME FOR SHADING ROBUSTNESS	,,,,,,,,,,		09/22/2011	2011-207152	JP
Granted	MIXED WIRING SCHEME FOR SHADING ROBUSTNESS	11/05/2014	2434552	09/21/2011	11182236.7	EP
Abandoned	MIXED WIRING SCHEME FOR SHADING ROBUSTNESS	11/25/2015	ZL201110285628.7	09/23/2011	201110285628.7	CN
Expired	REACTOR CLEAN			10/28/2010	PCT/US2010/054548	PC

	SHINGLED PHOTOVOLTAIC TILES AND FABRICATION PROCESSES THEREOF					
	PHOTOVOLTAIC MODULE CONTAINING			02/01/2013	13749204.7	ΕP
	FABRICATION PROCESSES THEREOF					
	SHINGLED PHOTOVOLTAIC TILES AND					
Abandoned	PHOTOVOLTAIC MODULE CONTAINING			02/01/2013	201380016212.2	CN
	FIBRICATION PROCESSES THEREOF					
	RIBBON BOND PHOTOVOLTAIC TILES AND					
	PHOTOVOLTAIC MODULE CONTAINING					SN
	PROCESS THEREOF					
	PHOTOVOLTAIC TILES AND FABRICATION					
	MONOLITHIC INTERCONNECTED					
Abandoned	PHOTOVOLTAIC MODULE CONTAINING					SN
	THEREOF					
Abandoned	MODULES AND FABRICATION PROCESSES				•	SN
	CONTAMINATION REMOVAL					
	SUBSTRATE CLEAN SOLUTION FOR COPPER			03/07/2011	PCT/US2011/027401	PC
	CONTAMINATION REMOVAL					
	SUBSTRATE CLEAN SOLUTION FOR COPPER			03/05/2010	61/311226	SN
	CONTAMINATION REMOVAL					
	SUBSTRATE CLEAN SOLUTION FOR COPPER	05/12/2015	9,028,620 B2	03/07/2011	13/042379	SN
	EPITAXIAL LIFT OFF SYSTEMS AND METHODS			03/02/2011	PCT/US2011/026926	PC
	BASED EPITAXIAL LIFT OFF					
	METHODS AND APPARATUS FOR TAPE-					
	REDUCED ETCHANT CONSUMPTION			03/02/2010	61/309625	SN
	EPITAXIAL LIFT OFF SYSTEMS AND METHODS	04/16/2019	10259206 B2	03/02/2011	13/039307	US
	EPITAXIAL LIFT OFF SYSTEMS AND METHODS	07/05/2016	9,381,731 B2	05/19/2014	14/281386	SN
Abandoned	HIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS	,,,,,,,,,		10/14/2010	99135012	™
	III/V MATERIALS					
	HIGH GROWTH DEPOSITION FOR GROUP			10/14/2010	PCT/US2010/052714	PC
	METHOD OF HIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS	12/05/2017	9,834,860 B2	10/13/2010	12/904090	SN
	GROUP III/V MATERIALS	<b></b>	;;;;;;;;;;;;;;;;;;;;;;;;;;;;;;;;;;;;;;		<del>}</del>	
	HIGH GROWTH RATE DEPOSITION FOR			10/14/2009	61/251677	US
T	GROUP III/V MATERIALS			10/14/2010	10824114.2	Ţ
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	FABRICATION					
Pending	METALLIC CONTACTS FOR PHOTOVOLTAIC			10/14/2011	2011-226920	JР
Closed	METALLIC CONTACTS FOR PHOTOVOLTAIC  DEVICES AND LOW TEMPERATURE  FABRICATION				11187679.3	Ę
Pending	DEVICES AND LOW TEMPERATURE FABRICATION			10/26/2011	201110328908.1	Ç
Closed	CHAMBER WITHIN ENCLOSED SYSTEM (CHAMBER INSIDE CHAMBER)					SN
Granted	TILED SHOWERHEAD FOR A SEMICONDUCTOR CHEMICAL VAPOR DEPOSITION REACTOR	11/03/2015	9,175,393 B1	08/31/2011	13/222890	Sn
Granted	TILED SHOWERHEAD FOR A SEMICONDUCTOR CHEMICAL VAPOR DEPOSITION REACTOR	12/01/2020	ZL201510963868.6	12/21/2015	201510963868.6	CN
Granted	TILED SHOWERHEAD FOR A SEMICONDUCTOR CHEMICAL VAPOR DEPOSITION REACTOR	09/04/2018	10066297 B2	10/27/2015	14/924488	Sn
Closed	THERMAL BRIDGE FOR CHEMICAL VAPOR DEPOSITION REACTORS			08/31/2012	12182540.0	EP
Granted	THERMAL BRIDGE FOR CHEMICAL VAPOR DEPOSITION REACTORS	05/09/2017	9,644,268 B2	08/31/2011	13/222984	SN
Closed	MOVABLE LINER ASSEMBLY FOR A DEPOSITION ZONE IN A CVD REACTOR			08/31/2012	12182530.1	EP
Granted	MOVABLE LINER ASSEMBLY FOR A DEPOSITION ZONE IN A CVD REACTOR	05/29/2018	9982346 B2	08/31/2011	13/222881	Sn
Expired	PHOTOVOLTAIC MODULE CONTAINING SHINGLED PHOTOVOLTAIC TILES AND FABRICATION PROCESSES THEREOF			02/01/2013	PCT/US2013/024411	PC
Granted	PHOTOVOLTAIC MODULE CONTAINING SHINGLED PHOTOVOLTAIC TILES AND FABRICATION PROCESSES THEREOF	08/11/2020	10741712 B2	02/15/2012	13/397487	Sn
Published	PHOTOVOLTAIC MODULE CONTAINING SHINGLED PHOTOVOLTAIC TILES AND FABRICATION PROCESSES THEREOF			02/01/2013	15105434.6	Ŧĸ

	GB	EP	CN	SN	WT	SN	KR	JP	ЕР	US	Sn	SN	CN	TW	US	Ã
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+ P + C - P	12154739.2	12154739.2	201210027952.3	13/210138	100139811	12/939077	10-2011-0112785	2011-226928	11187659.5	14/692647	13/451455	13/451439	201110329046.4	100136765	12/939050	10-2011-0112/81
02/03/2012	02/09/2012	02/09/2012	02/09/2012	08/15/2011		11/03/2010	11/01/2011	10/14/2011	11/03/2011	04/21/2015	04/19/2012	04/19/2012	10/26/2011		11/03/2010	11/01/2011
r - 0 - 2 - 1	2487712	2487712	ZL 2012 1 0027952.3	9,994,936 B2				5885238	2450956	9,954,131 B2	9,136,418 B2	9,178,099 B2				10-1380907
++/ 00/ +0+/	11/08/2017	11/08/2017	03/01/2017	06/12/2018				02/19/2016	09/04/2019	04/24/2018	09/15/2015	11/03/2015				05/26/2014
	SFI F-BYPASS DIODF FUNCTION FOR	SELF-BYPASS DIODE FUNCTION FOR GALLIUM ARSENIDE PHOTOVOLTAIC DEVICES	METHODS FOR GALLIUM ARSENIDE BASED PHOTOVOLTAIC DEVICES AND GALLIUM ARSENIDE BASED PHOTOVOLTAIC DEVICES	OFF-AXIS EPITAXIAL LIFT OFF PROCESS	OPTOELECTRONIC DEVICES INCLUDING HETEROJUNCTION AND INTERMEDIATE LAYER	OPTOELECTRONIC DEVICES INCLUDING HETEROJUNCTION AND INTERMEDIATE LAYER	METHODS FOR FORMING OPTOELECTRONIC DEVICES INCLUDING HETEROJUNCTION	OPTOELECTRONIC DEVICES INCLUDING HETEROJUNCTION	METALLIC CONTACTS FOR PHOTOVOLTAIC DEVICES AND LOW TEMPERATURE FABRICATION	METALLIC CONTACTS FOR PHOTOVOLTAIC DEVICES AND LOW TEMPERATURE FABRICATION	DEVICES AND LOW TEMPERATURE FABRICATION					
5	Granted	Granted	Granted	Granted	Abandoned	Abandoned	Published	Granted	Granted	Granted	Granted	Granted	Abandoned	Closed	Abandoned	Gigillen

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13/222310	77,777	14/480147	101111442	13/077353	12161877.1	201510367965.9	201210085259.1			- 1	14/183349	13/078722		2,772,892	13/023925			201210027953.8		13/023844			101104046			13/023733		10-2012-0013069
08/31/2011	\$ \$00/11/0011	09/08/2014	03/30/2012	03/31/2011	03/28/2012	03/28/2012	03/28/2012		•••••		02/18/2014	04/01/2011		03/30/2012	02/09/2011	\$	*******	02/09/2012		02/09/2011						02/09/2011		02/09/2012
8,846,417	0 0 1 7 1 7 0	9,647,148 B2		8,403,315		ZL201510367965.9	ZL 201210085259.1				9,142,707	8,657,994														9,716,196 B2		
09/30/2014	00/20/2014	05/09/2017		03/26/2013		05/01/2018	07/29/2015				09/22/2015	02/25/2014						,,,,,	,,,,,,				,,,,,			07/25/2017		
DEVICE AND METHOD FOR INDIVIDUAL FINGER ISOLATION IN AN OPTOELECTRONIC DEVICE	DEVICE AND METIOD FOR INDIVIDUAL	DEVICE FOR INDIVIDUAL FINGER ISOLATION IN AN OPTOELECTRONIC DEVICE	FILM TRANSFER FRAME	ASSEMBLY IN A CYLYNDRICAL CONFIGURATION	FLEXIBLE PHOTOVOLTAIC DEVICES	EPITAXIAL LIFT OFF	SYSTEM AND METHOD FOR IMPROVED	SYSTEM AND METHOD FOR IMPROVED EPITAXIAL LIFT OFF	EPITAXIAL LIFT OFF	SYSTEM AND METHOD FOR IMPROVED	NON-ANNEALED METAL CONTACT TO SEMICONDUCTOR MATERIAL	DEVICES	WINDOW ETCH STOP FOR PHOTOVOLTAIC	METAL CONTACT FORMATION AND	DEVICES	METAL CONTACT FORMATION AND WINDOW ETCH STOP FOR PHOTOVOLTAIC	DEVICES	GALLIUM ARSENIDE PHOTOVOLTAIC	SELF-BYPASS DIODE FUNCTION FOR	DEVICES	GALLIUM ARSENIDE PHOTOVOLTAIC	SELF-BYPASS DIODE FUNCTION FOR	DEVICES	SELF-BYPASS DIODE FUNCTION FOR				
Granted	C-2-t-1	Granted	Abandoned	Granted	Abandoned	Granted	Granted		Closed		Granted	Abandoned		Abandoned	Abandoned			Abandoned		Abandoned	***************************************		Closed			Granted		Published

	FROM TEMPLATE LAYER			······		
	FRONT AND/OR BACK SURFACE PREPARED					
	OPTOELECTRONIC DEVICE WITH TEXTURED					
Granted	THIN-FILM SEMICONDUCTOR	11/22/2016	9,502,594 B2	08/05/2014	14/452393	SN
	ANGLE RANDOMIZATION OF LIGHT					
	OPTOELECTRONIC DEVICE FOR IMPROVED					
Granted	TEXTURING A LAYER IN AN	01/03/2017	9,537,025	04/24/2015	14/696106	SN
•••••	FABRICATION METHOD					
	OPTOELECTRONIC DEVICE AND					
	SPOT APPLICATION OF A DIELECTRIC IN AN					
Granted	INDIVIDUAL FINGER ISOLATION THROUGH	11/21/2015	1509825	11/04/2011	100140288	WT
	OPTOELECTRONIC DEVICE					
	SPOT APPLICATION OF A DIELECTRIC IN AN					
Granted	INDIVIDUAL FINGER ISOLATION THROUGH	07/04/2017	9,698,284 B2	08/31/2011	13/222393	SN
	PHOTOVOLTAIC CELLS					
Granted	METHOD AND APPARATUS FOR ASSEMBLING	09/08/2015	9,130,093 B2	08/31/2011	13/223242	SN
	DICING OF SEMICONDUCTOR FILMS					
Granted	ALIGNED FRONTSIDE BACKSIDE LASER	01/29/2013	8,361,828 B1	08/31/2011	13/222750	SN
	MATERIALS SEPARATED BY A METAL FOIL	,,,,,				
Granted	LASER CUTTING THROUGH TWO DISSIMILAR	05/20/2014	8,728,849 B1	08/31/2011	13/222686	SN
	SEMICONDUCTOR FILMS					
Granted	TWO BEAM BACKSIDE LASER DICING OF	03/19/2013	8,399,281 B1	08/31/2011	13/222617	SN
	FOR THIN-FILM SOLAR CELLS					
Granted	LASER CUTTING AND CHEMICAL EDGE CLEAN	05/20/2014	8,728,933 B2	08/31/2011	13/223133	SN
	WALLS					
Closed	CVD REACTOR WITH GAS FLOW VIRTUAL			08/31/2012	12182559.0	EP
	WALLS					
Granted	CVD REACTOR WITH GAS FLOW VIRTUAL	12/15/2015	9,212,422 B2	08/31/2011	13/222840	SN
	OPTOELECTRONIC DEVICE	,,,,,,				
Closed	PHOTON RECYCLING IN AN			11/25/2011	100143414	WT
	OPTOELECTRONIC DEVICE			,		
Closed	PHOTON RECYCLING IN AN			06/06/2011	61/493936	SN
	OPTOELECTRONIC DEVICE					
Closed	PHOTON RECYCLING IN AN			08/31/2011	13/223187	SN
	DEVICE DEVICE					
Abandoned	DEVICE AND METHOD FOR INDIVIDUAL			11/03/2011	100140083	W
		,		,		

	CHEMICAL VAPOR DEPOSITION REACTOR					
Granted	REFLECTOR AND SUSCEPTOR ASSEMBLY FOR	02/23/2021	10932323	08/03/2015	14/817037	SN
Pending	REFLECTOR AND SUSCEPTOR ASSEMBLY FOR CHEMICAL VAPOR DEPOSITION REACTOR			10/10/2015	201510651165.X	CN
Abandoned	FRAMES FOR THIN SEMINCONDUCTOR FILMS TO ENABLE WAFER-LIKE HANDLING					Sn
Abandoned	JOINDER STRUCTURE FOR SOLAR CELLS  ARRAYS	,,,,,,,,,				Sn
Granted	FASTENER SYSTEM FOR SUPPORTING A LINER PLATE IN A GAS SHOWERHEAD REACTOR	02/23/2016	9,267,205	05/30/2012	13/483779	SN
Granted	MULTI-JUNCTION OPTOELECTRONIC DEVICE	09/19/2017	9,768,329 B1	12/04/2012	13/705064	SO
Published	SUBSTRATE PROCESSING USING INTERLEAVED LOAD LOCK TRANSFERS			03/26/2015	14/669250	Sn
Pending	SUBSTRATE PROCESSING USING INTERLEAVED LOAD LOCK TRANSFERS			07/09/2015	201510400241.X	CN
Granted	PROCESSING SYSTEM ARCHITECTURE WITH SINGLE LOAD LOCK CHAMBER	05/10/2016	9,337,014	03/08/2013	13/790326	Sn
Granted	HIGH THROUGHPUT POLISHING SYSTEM FOR WORKPIECES	04/24/2018	9,950,404 B1	03/29/2012	13/434726	Sn
Granted	FIXTURE FOR SUBSTRATE CUTTING	08/25/2015	9,114,464	03/14/2012	13/420414	SN
Closed	OPTOELECTRONIC DEVICE WTH NON- CONTINUOUS BACK CONTACTS	,,,,,,,,,				PC
Published	OPTOELECTRONIC DEVICE WTH NON- CONTINUOUS BACK CONTACTS			04/13/2012	13/446876	Sn
Closed	OPTOELECTRONIC DEVICE WTH NON- CONTINUOUS BACK CONTACTS	,,,,,,,,,,				Sn
Abandoned	DIFFUSERS FOR MAKING THERMAL GRADIENT SHOWERHEADS IN A MOCVD REACTOR			12/09/2011	13/316343	SN
Abandoned	DIFFUSERS WITH FRACTAL GAS PATHS IN THERMAL GRADIENT SHOWERHEADS	<i></i>		03/14/2012	13/420390	SO
Granted	TEXTURING A LAYER IN AN OPTOELECTRONIC DEVICE FOR IMPROVED ANGLE RANDOMIZATION OF LIGHT	09/15/2015	9,136,422	01/19/2012	13/354175	Sn
Granted	THIN-FILM SEMICONDUCTOR  OPTOELECTRONIC DEVICE WITH TEXTURED  FRONT AND/OR BACK SURFACE	05/11/2018	ZL201510475349.5	08/05/2015	201510475349.5	CN

US 14/994889		US	US 14/858808	US 14/918043	US 62/184712				20							
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01/13/2016		,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,	09/18/2015	10/20/2015	06/25/2015	03/20/2015		09/11/2014								
10693027 B2			9,711,671 B2	10483410 B2		9,859,162			ZL 201510184183.1	71 201510184183.1	71 201510184183.1	ZL 201510184183.1	ZL 201510184183.1	21 201510184183.1	ZL 201510184183.1	ZL 201510184183.1
06/23/2020			07/18/2017	11/19/2019		01/02/2018	*************		06/04/2019							
METHOD FOR INTERCONNECTING SOLAR CELLS	MULTIFUNCTION III-V/SI SOLAR CELL PRODUCED BY WAFER BONDING AND EPITAXIAL LIFT-OFF PROCESS	MULTIFUNCTION OPTOELECTRONIC DEVICE BY LIFTOFF AND BONDING AND SECOND LIFTOFF	VIA STRUCTURES FOR SOLAR CELL INTERCONNECTION IN SOLAR MODULE	FORMING FRONT METAL CONTACT ON SOLAR CELL WITH ENHANCED RESISTANCE TO STRESS	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE AND METHOD OF USE	PERFORATION OF FILMS FOR SEPARATION		PERFORATION OF FILMS FOR SEPARATION	PERFORATION OF FILMS FOR SEPARATION  PERFORATION OF FILMS FOR SEPARATION	OPTOELECTRONIC DEVICE WITH DIELECTRIC LAYER AND METHOD OF MANUFACTURE PERFORATION OF FILMS FOR SEPARATION PERFORATION OF FILMS FOR SEPARATION		MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION CORDLESS SOLAR CHARGER OPTOELECTRONIC DEVICE WITH DIELECTRIC LAYER AND METHOD OF MANUFACTURE PERFORATION OF FILMS FOR SEPARATION PERFORATION OF FILMS FOR SEPARATION	MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION CORDLESS SOLAR CHARGER OPTOELECTRONIC DEVICE WITH DIELECTRIC LAYER AND METHOD OF MANUFACTURE PERFORATION OF FILMS FOR SEPARATION	TRIPLE JUNCTION OPTOELECTRONIC DEVICE WITH GAAS AS THE BOTTOM ABSORBER MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION CORDLESS SOLAR CHARGER OPTOELECTRONIC DEVICE WITH DIELECTRIC LAYER AND METHOD OF MANUFACTURE PERFORATION OF FILMS FOR SEPARATION	THIN FILM INGAP OPTOELECTRONIC DEVICE TRIPLE JUNCTION OPTOELECTRONIC DEVICE WITH GAAS AS THE BOTTOM ABSORBER MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION CORDLESS SOLAR CHARGER OPTOELECTRONIC DEVICE WITH DIELECTRIC LAYER AND METHOD OF MANUFACTURE PERFORATION OF FILMS FOR SEPARATION	THIN FILM III-IV OPTOELECTRONIC DEVICE OPTIMIZED FOR NON-SOLAR ILLUMINATION SOURCES THIN FILM INGAP OPTOELECTRONIC DEVICE TRIPLE JUNCTION OPTOELECTRONIC DEVICE WITH GAAS AS THE BOTTOM ABSORBER MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION CORDLESS SOLAR CHARGER OPTOELECTRONIC DEVICE WITH DIELECTRIC LAYER AND METHOD OF MANUFACTURE PERFORATION OF FILMS FOR SEPARATION
Granted	Closed	Closed	Granted	Granted	Expired	Granted	Expired	Granted		Published	Expired Published	Expired Expired Published	Published Expired Expired Published	Closed Published Expired Expired Published	Expired Closed Published Expired Expired Published	Abandoned Expired Closed Published Expired Published

	WITH SO METHOD AND SY EFFLUENT TAPE-BASED EF APPARATUSES VAPOR DEPOSITIO WAFER CA REACTOR LID ASS DEPC HEATING L	02/12/2019		03/16/2009	61/160699	US
	WITH SO  METHOD AND SY EFFLUENT  TAPE-BASED EF APPARATUSES  VAPOR DEPOSITIO  WAFER CA  REACTOR LID ASS DEPC	02/12/2019		÷	G+/ ±00,00	
	WITH SO  METHOD AND SY  EFFLUENT  TAPE-BASED EF  APPARATUSES  VAPOR DEPOSITIO  WAFER CA  REACTOR LID ASS	02/12/2019			C+/ + C - C - C - C - C - C - C - C - C - C	;
	WITH SO METHOD AND SY EFFLUENT TAPE-BASED EF APPARATUSES VAPOR DEPOSITIO WAFER CA	02/12/2019	****	03/16/2009	61/160703	US
	WITH SO METHOD AND SY EFFLUENT TAPE-BASED EF APPARATUSES VAPOR DEPOSITIO	02/12/2019	***************************************	03/16/2009	61/160696	SN
	WITH SO METHOD AND SY EFFLUENT TAPE-BASED EF APPARATUSES	02/12/2019		03/16/2009	61/160690	SN
	WITH SO METHOD AND SY EFFLUENT		10204831 B2	09/22/2015	14/861821	Sn
	WITH SO			06/29/2018	PCT/CN2018/093525	PC
N FOR MOBILE DEVICE Expired	CHARGING STATION	,,,,,,,,,,		01/22/2016	PCT/US2016/014508	PC
SURFACTANTS  SURFACTANTS  SURFACTANTS	GAASSURFACE PASSI AND SELENIUM SURFA				2499082	S
	OPTOELECTRONIC DE EFFICIENCY AND	05/31/2016	9,356,183	06/20/2012	13/528721	US
	WHISPERING GA			09/13/2011	PCT/US2011/051384	PC
RESONANT LIGHT ABSORPTION IN SOLAR Expired CELLS VIA WHISPERING GALLERY NANO AND MICROPHONES	RESONANT LIGHT A CELLS VIA WHISPERIN MICRC			06/17/2011	67/498282	Sn
RESONANT LIGHT ABSORPTION IN SOLAR Expired CELLS VIA WHISPERING GALLERY NANO AND MICROSPHERES	RESONANT LIGHT A CELLS VIA WHISPERIN MICRO			09/13/2010	61/382422	Sn
RESONANT LIGHT ABSORPTION IN SOLAR Abandoned CELLS VIA WHISPERING GALLERY NANO AND MICROSPHERES	RESONANT LIGHT A CELLS VIA WHISPERIN MICRO			09/13/2011	13/231111	Sn
	VERSATILE FL INTERCONNECTION CELLS TO SIMPLIFY IN VOLTAGE			12/08/2015	62/264751	Sn
LAMINATE GAAS MODULE Closed	A METHOD TO LAM			,,,,,,,		SN
METHOD FOR SELECTIVELY COLORING Abandoned METAL CONTACTS IN OPTOELECTRONIC DEVICE	METHOD FOR SELI METAL CONTACTS DE			01/13/2016	14/994961	Sn

	75/3			••••					PC PCT/US20		GB 1118		DE 1118		PC PCT/US20		PC PCT/US20				US 15/3		CN 201610		PC PCT/US20		rc1/0320		US 14/9			US 15/1		PC PCT/US20	
	13/3/2083					15/422218			PCT/US2016/057752		11182236.7		11182236.7		PCT/US2016/052127 (		PCT/US2016/052939 (	+			15/340560		201610836332.2		PCT/US2016/039411 (		FC1/032010/014000	-	14/989659 (			15/191410		PCT/US2016/039417 🚶 (	
	TZ/0//2010	7/07/2016				02/01/2017			10/19/2016		09/21/2011		09/21/2011   60		09/16/2016		09/21/2016				11/01/2016		10/26/2011 ZL	,,,,,,,	06/24/2016		21/20/2010	01/06/06/16	01/06/2016	03/16/2009		06/23/2016		06/24/2016	
	T0416955 DZ	10/19033 R7				,,,,,		,,,,,			2434552	·····	60 2011 011 059.4								10008628 B2		ZL 201610836332.2						9,853,489	<i></i>		10076896 B2			
**************************************	6102//1/60	00/17/2010									11/05/2014		11/05/2014								06/26/2018		06/11/2019						12/26/2017			09/18/2018			
CELLS	INTERCONNECTION FOR FLEXIBLE SOLAR	VERSATILE ELEVIBLE CIRCUIT	FROM ETCHING	FRONT AND/OR BACK SURFACE PREPARED	OPTOELECTRONIC DEVICE WITH TEXTURED	THIN-FILM SEMICONDUCTOR	TO STRESS	SOLAR CELL WITH ENHANCED RESISTANCE	FORMING FRONT METAL CONTACT ON	ROBUSTNESS	MIXED WIRING SCHEME FOR SHADING	ROBUSTNESS	MIXED WIRING SCHEME FOR SHADING	INTERCONNECTION IN SOLAR MODULE	VIA STRUCTURES FOR SOLAR CELL	LAYER AND ME I HOU OF MANOFACTORE	OPTOELECTRONIC DEVICE WITH DIELECTRIC	FROM TEMPLATE LAYER	FRONT AND/OR BACK SURFACE PREPARED	OPTOELECTRONIC DEVICE WITH TEXTURED	THIN-FILM SEMICONDUCTOR	HETEROJUNCTION	OPTOELECTRONIC DEVICES INCLUDING	MANUFACTURE OF PHOTOVOLTAIC CELLS	PRESSURIZED HEATED ROLLING PRESS FOR	SOURCES	OPTIMIZED FOR NON-SOLAR ILLUMINATION	WITH SOLAR PANEL	CHARGING STATION FOR MOBILE DEVICE	METHOD FOR VAPOR DEPOSITION	MANUFACTURE AND METHOD OF USE	PRESSURIZED HEATED ROLLING PRESS FOR	MANUFACTURE AND METHOD OF USE	PRESSURIZED HEATED ROLLING PRESS FOR	MANUFACTURE AND METHOD OF USE
	Granted	Granted				Allowed			Expired		Granted		Granted		Expired		Expired			,,,,,,	Granted		Granted		Expired	******	מי		Granted	Expired		Granted		Expired	

Allowed	MULTI-JUNCTION OPTOELECTRONIC DEVICE			09/15/2017	15/706090	SN
Granted	CHARGING STATION FOR MOBILE DEVICE WITH SOLAR PANEL	06/08/2020	6714005	01/22/2016	2017-538627	JP
Published	HIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS			09/27/2017	15/717694	SN
	GALLIUM ARSENIDE PHOTOVOLTAIC DEVICES					
Published	SELF-BYPASS DIODE FUNCTION FOR			07/21/2017	15/656575	SU
Pending	CHARGING STATION FOR MOBILE DEVICE WITH SOLAR PANEL			01/22/2016	10-2017-7023342	Ŕ
Granted	CHARGING STATION FOR MOBILE DEVICE WITH SOLAR PANEL	06/02/2020	ZL201680006837.4	01/22/2016	201680006837.4	CN
	OPTOELECTRONIC DEVICES					
Expired	GROWTH SUBSTRATE UNDER A RELEASE LAYER FOR MANUFACTURING OF			06/16/2017	62/521241	US
	APPARATUSES					
	APPARATUSES INCLUDING OPTO-ELECTRICAL					
Published	SUPPORT STRUCTURES FOR VARIOUS			08/31/2017	15/693062	SN
	PHOTOVOLTAIC DEVICES AND GALLIUM ARSENIDE BASED PHOTOVOLTAIC DEVICES					
Granted	METHODS FOR GALLIUM ARSENIDE BASED	12/21/2018	ZL201710057541.1	01/26/2017	201710057541.1	CN
	TOM JUNCTION					
Expired	MULTI-JUNCTION OPTOELECTRONIC DEVICE			01/27/2017	PCT/US2017/015387	PC
	DEVICE					
Expired	METHOD FOR SELECTIVELY COLORING  METAL CONTACTS IN OPTOELECTRONIC			01/12/2017	PCT/US2017/013241	PC
	CELLS					
Expired	METHOD FOR INTERCONNECTING SOLAR			01/12/2017	PCT/US2017/013230	PC
	RESIST STRIP PROCESS OF THIN FILM GAAS SOLAR CELLS					
	PLATING WITH ELECTROPLATING AND					
Abandoned	PALLADIUM SEED AND LIGHT ASSISTED					SN
	INTERCONNECTION FOR FLEXIBLE SOLAR CELLS			12/00/2010	101/03/04/03/04/	-
Eynired	A VERSATII E ELEXIBLE CIRCLIIT			12/08/2016	PCT/HS2016/065612	PC

	TO STRESS					
Pending	FORMING FRONT METAL CONTACT ON			10/19/2016	2018-512422	Þ
	TO STRESS					
	SOLAR CELL WITH ENHANCED RESISTANCE					
Published	FORMING FRONT METAL CONTACT ON			10/19/2016	201680061819.6	CN
	TO STRESS					
	SOLAR CELL WITH ENHANCED RESISTANCE					•••••
Published	FORMING FRONT METAL CONTACT ON			10/19/2016	16787699.4	EP
	INTERCONNECTION IN SOLAR MODULE	,,,,,,				
Granted	VIA STRUCTURES FOR SOLAR CELL	09/04/2019	3350843	09/16/2016	16770656.3	EP
	INTERCONNECTION IN SOLAR MODULE					
Granted	VIA STRUCTURES FOR SOLAR CELL	10/06/2020	6774086	09/16/2016	2018-512282	Þ
	INTERCONNECTION IN SOLAR MODULE	,,,,,,				
Pending	VIA STRUCTURES FOR SOLAR CELL			09/16/2016	10-2018-7010172	KR
	INTERCONNECTION IN SOLAR MODULE					
Published	VIA STRUCURES FOR SOLAR CELL			09/16/2016	201680054147.6	CN
	MANUFACTURE AND METHOD OF USE					
Published	PRESSURIZED HEATED ROLLING PRESS FOR			06/24/2016	2018-7002492	KR
		,,,,,,				
Granted	PRESSURIZED HEATED ROLLING PRESS FOR	07/24/2019	3314640	06/24/2016	16741433.3	EP
	MANUFACTURE AND METHOD OF USE					
Published	PRESSURIZED HEATED ROLLING PRESS FOR			06/24/2016	201680044893.7	CN
	MANUFACTURE OF PHOTOVOLTAIC CELLS					
Published	PRESSURIZED HEATED ROLLING PRESS FOR			06/24/2016	2018-7002494	KR
		,,,,,,				
Granted	PRESSURIZED HEATED ROLLING PRESS FOR	07/24/2019	3314639	06/24/2016	16745889.2	EP
	MANUFACTURE OF PHOTOVOLTAIC CELLS					******
Published	PRESSURIZED HEATED ROLLING PRESS FOR			06/24/2016	201680045097.5	CN
Abandoned	PLANARIZATION OF PHOTOVOLTAICS			06/11/2018	16/005289	SN
	JUNCTIONS					
	LATTICE-MATCHED DILUTE NITRIDE					
	OPTOELECTRONIC DEVICES INCORPORATING					•••••
Granted	THIN-FILM, FLEXIBLE MULTI-JUNCTION	03/10/2020	10586884 B2	06/18/2018	16/011516	SN
	DEVICES	,,,,,,				
Granted	SELF-BYPASS DIODE FUNCTION FOR GALLIUM ARSENIDE PHOTOVOLTAIC	01/06/2021	3297026	02/09/2012	17198268.9	ΕP
	,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,	,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,		Å	y	ç

Published	A VERSATILE FLEXIBLE CIRCUIT INTERCONNECTION FOR FLEXIBLE SOLAR CELLS			12/08/2016	16820083.0	EP
Pending	A VERSATILE FLEXIBLE CIRCUIT INTERCONNECTION FOR FLEXIBLE SOLAR CELLS			12/08/2016	2018-529132	JP
Pending	A VERSATILE FLEXIBLE CIRCUIT INTERCONNECTION FOR FLEXIBLE SOLAR CELLS	,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,		12/08/2016	10-2018-7019423	KR
Published	A VERSATILE FLEXIBLE CIRCUIT INTERCONNECTION FOR FLEXIBLE SOLAR CELLS			12/08/2016	201680072342.1	CN
Granted	OPTOELECTRONIC DEVICES INCLUDING HETEROJUNCTION AND INTERMEDIATE LAYER	02/09/2021	10916676 B2	04/20/2018	15/958844	SN
Published	HIGH THROUGHPUT POLISHING SYSTEM FOR WORKPIECES	,,,,,,,,,,		04/13/2018	15/953064	SN
Published	THIN-FILM SEMICONDUCTOR OPTOELECTRONIC DEVICE WITH TEXTURED FRONT AND/OR BACK SURFACE PREPARED FROM TEMPLATE LAYER			04/16/2018	201810340115.3	CN
Abandoned	OFF-AXIS EPITAXIAL LIFT PROCESS			03/23/2018	15/934409	SN
Granted	THIN-FILM, FLEXIBLE OPTOELECTRONIC DEVICES INCORPORATING A SINGLE LATTICE- MATCHED DILUTE NITRIDE JUNCTION AND METHODS	10/06/2020	10797197B2	06/18/2018	16/011531	Sn
Published	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE AND METHOD OF USE	,,,,,,		03/23/2018	15/934380	SN
Granted	OFF-AXIS EPITAXIAL LIFT OFF PROCESS	07/02/2019	10337087 B2	01/19/2018	15/876001	SN
Granted	OPTOELECTRONIC DEVICE WITH DIELECTRIC LAYER AND METHOD OF MANUFACTURE	04/07/2020	10615304 B2	12/11/2017	15/837533	SN
Published	CHARGING STATION FOR MOBILE DEVICE WITH SOLAR PANEL			11/10/2017	15/809576	SN
Pending	FORMING FRONT METAL CONTACT ON SOLAR CELL WITH ENHANCED RESISTANCE TO STRESS			10/19/2016	10-2018-7014341	KR.

Expired	GROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES			06/15/2018	PCT/US2018/037759	PC
	LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES					
Granted	CELLS GROWTH STRUCTURE UNDER A RELEASE	10/20/2020	10811557 B2	06/14/2018	16/008919	SU
Pending	METHOD FOR INTERCONNECTING SOLAR			01/12/2017	10-2018-7023275	KR
Pending	METHOD FOR INTERCONNECTING SOLAR CELLS			01/12/2017	2018-532251	JP
Granted	INTERCOI CELLS	10/30/2019	3403283	01/12/2017	17702212.6	EP
Published	METHOD FOR INTERCONNECTING SOLAR CELLS			01/12/2017	201780007438.4	CN
Abandoned	MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION	,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,		01/27/2017	17703637.3	EP
Pending	MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION			01/27/2017	10-2018-7024392	KR
Pending	MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION	,,,,,,		01/27/2017	2018-537648	JP
Published	MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION			01/27/2017	201780008978.4	CN
Granted	METHODS FOR CHEMICAL VAPOR DEPOSITION (CVD) IN A MOVABLE LINER ASSEMBLY	07/21/2020	10718051 B2	05/04/2018	15/971571	Sn
Published	AUTOMATED LINEAR VACUUM DISTRIBUTION VALVE	,,,,,,,,,,		10/02/2018	16/149893	SN
Closed	PHOTOVOLTAIC DEVICE INCLUDING SCHOTTKY JUNCTION BETWEEN III-V SEMICONDUCTOR AND TRANSPARENT CONDUCTOR					NS
Published	MULTI-JUNCTION OPTOELECTRONIC DEVICE WITH GROUP IV SEMICONDUCTOR AS A BOTTOM JUNCTION			04/19/2018	15/957446	Sn

	CONTINUOUS BACK CONTACTS		***************************************	***************************************		
Published	OPTOELECTRONIC DEVICE WITH NON-			11/16/2018	16/194029	SN
Expired	HARVESTABLE INDOOR ENERGY METER			10/17/2018	62/746971	SN
	THROUGHPUT					
Published	SPUTTERED THEN EVAPORATED BACK			04/30/2019	16/399012	SN
	DEVICES					
Published	ENERGY DEVICE FOR USE IN ELECTRONIC			01/31/2019	16/264324	SN
(	LIFTOFF PROCESS			,		
Pending	WAFER BASE FOR HIGH SPEED EPITAXIAL			08/27/2020	63/071246	SN
	HOLDING WET EQUIPMENT	,,,,,,				
Pending	A DEVICE AND METHOD OF LIFTING AND			07/23/2018	201821168128.9	CN
	HOLDING WET EQUIPMENT				••••	
Pending	A DEVICE AND METHOD OF LIFTING AND			07/23/2018	201810813474.6	S
	SEPARATION METHOD	,,,,,				
Pending	A WAFER SEPARATION DEVICE AND			07/20/2018	201821155549.8	CN
	SEPARATION METHOD					
Pending	A WAFER SEPARATION DEVICE AND			07/20/2018	201810806187.2	CN
	SURFACE					
	GRID LINES WITH A BLACK COATING ON ITS					
	MODULE IMPLEMENTING METALLIC COPPER					
Pending	A SOLAR ENERGY ABSORBING DEVICE AND			08/28/2020	63/071757	SN
	SYSTEMS WITH HIGH ETCH SELECTIVITY					
Pending	FIXTURE DESIGN FOR EPITAXIAL LIFT-OFF			08/27/2020	63/071266	SN
	GROUP III/V MATERIALS	,,,,,				
Expired	HIGH GROWTH RATE DEPOSITION FOR			09/07/2018	PCT/US2018/049869	PC
	SHOWERHEADS IN A MOCVD REACTOR					,
Closed	DIFFUSER FOR MAKING THERMAL GRADIENT					SU
******	DIFFERENT GROWTH SUBSTRATES					
9	OPTOELECTRONIC DEVICES LISING	,,		,,		
Granted	METHODS OF MANUFACTURING	12/22/2020	10873001 B2	10/18/2019	16/657802	US
	USING DIFFERENT GROWTH SUBSTRATES					
Published	OPTOELECTRONIC DEVICES MANUFACTURED			10/18/2019	16/657765	SN
	JUNCTION					
	WITH GROUP III-IV-V SEMICONDUCTOR AS A				•••••	
Closed	MULTI-JUNCTION OPTOELECTRONIC DEVICE					SN
Closed	MULTIJUNCTION LED MANUFACTURED USING ELO PROCESS				•••••	SN
		,			-	

	CENTICONDITICATOR DEVICE DECORESSINO		•••••	
Expired	METHODS AND SYSTEMS FOR ALIGNMENT	03/07/2019	62/815185	SN
	FABRICATION PROCESSES THEREOF			
	SHINGLED PHOTOVOLTAIC TILES AND			
Published	PHOTOVOLTAIC MODULE CONTAINING	06/24/2019	201910548576.4	CN
	TO STRESS			
	SOLAR CELL WITH ENHANCED RESISTANCE			
Published	FORMING FRONT METAL CONTACT ON	05/30/2019	16/427142	SN
	ELECTROCHEMICAL ARSINE GENERATION			
Pending	SYSTEMS AND METHODS FOR HIGH-RATE	09/10/2020	63/076582	SN
	DEPOSITION SYSTEMS			
Published	METHODS AND SYSTEMS FOR CLEANING	05/07/2019	16/405347	SN
(10000				Ç
Closed	TRIMETHYLINDILIM VADOR STATION DESIGN			SII
0.00	LIFT-OFF USING SMALL ETCHANT VOLUMES	00/20/2020	03/0/1023	č
Dending	METHOD AND ADDARATIC FOR EDITAYIAI	08/28/2020	63/071820	
	EPITAXIAL LIFT-OFF (ELO) PROCESSING			
0	ETCHANT IN A GASEOUS STATE DURING			;
Pending	SYSTEMS AND METHODS FOR SUPPLYING AN	08/28/2020	63/071747	SN
Published	FRONT METAL CONTACT STACK	03/29/2019	16/370473	SN
	ABLATION			
	SEMICONDUCTORS BY MELTING AND			
Published	LASER-TEXTURED THIN-FILM	04/02/2019	16/373305	SN
	CONTINUOUS BACK CONTACTS			
Abandoned	OPTOELECTRONIC DEVICE WTH NON-	11/21/2018	16/198139	SN
	MULTI-POINT PROBE			
	MATERIAL USING A NON-DESTRUCTIVE			
	ELECTRICAL CHARACTERISTICS OF A			
Published	SYSTEMS AND METHODS FOR MEASURING	07/02/2019	16/460432	SN
	DEVICES			
	GALLIUM ARSENIDE PHOTOVOLTAIC			
Published	SELF-BYPASS DIODE FUNCTION FOR	02/15/2019	16/277749	SN
	TRANSPARENT CONDUCTIVE LAYER			
Pending	BIFACIAL OPTOELECTRONIC DEVICE WITH	08/27/2020	63/071173	SN
	CELLS USING AN ADHESIVE FILM			
Published	SYSTEMS AND METHODS FOR SHINGLING	01/25/2019	16/257569	SN
	CONTINUOUS BACK CONTACTS		`	
Published	OPTOELECTRONIC DEVICE WTH NON-	11/21/2018	16/198124	C

12/30/2020 PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE AND METHOD OF USE
OPTOELECTRONIC DEVICES INCLUDING HETEROJUNCTION
12/10/2019
THERMOCOUPLE SPOOL WINDER
<b></b>
GAS TRAP SYSTEM HAVING A CONIDENSATION REGION
GAAS BASED PV DEVICES
LIFT-OFF (ELO) FILMS BACKGROUND
COLOR-CODED PATTERNS FOR EPITAXIAL
PHOTOVOLTAIC DEVICES INCLUDING
OPTOELECTRON
THIN-FILM, FLE
MAICHEU DILUIE NIIRIDE JUNCIION AND
DEVICES INCORPORATING A SINGLE LATTICE
THIN-FILM, FI
INTERCONNECT
INFRARED IMAGING OF SEMICONDUCTOR FILM
METHODS AND SYSTEMS FOR IDENTIFYING FEATURES
METHODS AND SYSTEMS FOR REDUCING
PLANARIZATION OF PHOTOVOLTAICS

06/24/2015 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOXOLTAIC CELLS 05/14/2019 SUPPRESE PASSIVATION OF III-V OPTOELECTRONIC OEVICES (MODULES INCORPORATING ENCAPSULATION LAYERS OP/10/2020 SYSTEMS AND METHODS FOR LARGE ESCALE GROUP III/Y METHODS FOR LARGE ESCALE EFFLUENT ABATEMENT 06/29/2018 EXTERNAL STRESS ASSISTED EPITAXIAL LIFT-OF FRUENT ABATEMENT 06/29/2018 EXTERNAL STRESS ASSISTED EPITAXIAL LIFT-OF FRUENT ABATEMENT 06/29/2018 METHOD AND SYSTEM FOR MOCVD EFFLUENT ABATEMENT 06/29/2018 METHOD AND SYSTEM FOR EFFLUENT ABATEMENT 06/29/2018 METHOD AND SYSTEM FOR EFFLUENT ABATEMENT 06/29/2018 METHOD AND SYSTEM FOR EFFLUENT ABATEMENT 06/29/2018 MATCHED DILUTE NITRIDE JUNCTION AND METHOD AND SYSTEM FOR EFFLUENT ABATEMENT 06/29/2019 METHOD AND SYSTEM FOR SINGLE LATTICE-MATCHED DILUTE NITRIDE JUNCTION AND METHOD AND SYSTEM FOR EFFLUENT ABATEMENT 06/29/2019 MATCHED DILUTE NITRIDE JUNCTION AND		METHODS					
06/24/2016 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS 505/14/2019 SURFACE PASSIVATION OF III.V OPTOELECTRONIC DEVICES 10/03/2019 PROTOCELECTRONIC DEVICES MADULES INCORPORATING ENVICES 110/03/2019 PROTOCELECTRONIC DEVICES MODULES INCORPORATING ENVICES O5/14/2019 PROTOCED ENVICES MODULES INCORPORATING ENVICES O5/14/2019 PROTOCED ENVICES INCORPORATING ENVICES INCORPORATING ENVICES INCORPORATING ENVICES INCORPORATING ENVICES INCORPORATING STEM FOR MODULES INCORPORATING STEM FOR MODULES INCORPORATING A SINGLE LATTICE-INCORPORATING A SINGLE L		MATCHED DILUTE NITRIDE JUNCTION AND					
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06/24/2016 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS SURFACE PASSIVATION OF III-V OPTOLECTRON/OLTAIC CELLS II/O/37/2019 SURFACE PASSIVATION CAPERS MODULES INCORPORATING ENCAPSULATION LAYERS OS/14/2019 HIGH GROWH HATE DEPOSITION FOR GROUP III/V MATERIALS SYSTEM SAND METHODS FOR LARGE SCALE GAS GENERATION EXTERNS AND METHODS FOR LARGE SCALE GAS GENERATION EXTERN SASSISTED EPITAXIAL LIFT-OF METHOD AND SYSTEM FOR MOCVOLTAICS MOCKOLTAICS METHOD AND SYSTEM FOR MOCVOLTAICS METHO	Published	EXIBLE OPTOELECTRONIC			03/22/2019	201980001932.9	CN
06/24/2016  06/24/2016  06/24/2016  05/14/2019  05/14/		METHODS	,,,,,				
06/24/2016  06/24/2015  06/24/2019  05/14/		MATCHED DILUTE NITRIDE JUNCTION AND					
06/24/2016  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/10/2020  05/14/2019  05/10/2020  05/10/2020  EXTERNAL STRESS ASSISTED EPITAXIAL LIFT-OFF METHOD AND SYSTEM FOR MOCVD EFFLUENT ABATEMENT  06/29/2018		DEVICES INCORPORATING A SINGLE LATTICE-					
06/24/2016  06/24/2016  3550597  01/20/2021  PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS  SURFACE PASSIVATION OF III-V OPTOELECTRONIC OBSITION OF OIII-V OPTOELECTRONIC OBSITION FOR ENCAPSULATION OF III-V OPTOELECTRONIC OBSITION FOR ENCAPSULATION LAYERS  10/03/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  06/29/2018	Closed	LEXIBLE OPT			03/22/2019		EP
06/24/2016 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS  05/14/2019 SUFFACE PASSIVATION OF III-V 07/03/2019 PRESSIVATION CENTRES ASSISTED PORTATING ENCAPSULATION LAYERS 09/10/2020 SYSTEMS AND METHODS FOR LARGE SCALE GAS GENERATION EXTERNAL STRESS ASSISTED PORTAXIAL LIFT- 06/29/2018 PRESSIVE OF THIN PORTAXIAL LIFT- 06/29/2018 PRESSIVE OF THIN PORTAXIAL LIFT- 06/29/2018 PRESSIVE OF PORTAXIAL LIFT- 06/29/2018 PRESSIVE OF PORTAXIAL LIFT- 06/29/2018 PRESSIVATION EXTERNAL STRESS ASSISTED PORTAXIAL LIFT- 07F METHOD AND SYSTEM FOR MOCVD EFFLUENT ABATEMENT		ABATEMEN"					
06/24/2016  06/24/2016  06/24/2019  05/14/2019  05/14/2019  10/03/2019  10/03/2019  10/03/2019  06/29/2018	Pending	METHOD AND SYSTEM FOR EFFLUENT			06/29/2018	2019-552625	JP
06/24/2016  06/24/2016  06/24/2019  06/24/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  05/14/2019  06/29/2018		EFFLUENT ABATEMENT					
06/24/2016  06/24/2019  05/14/2019  05/29/2018  06/29/2018  06/29/2018  06/29/2018  06/28/2019  06/28/2019  06/28/2019  06/28/2019  06/28/2019  06/20/2018  06/20/2018  06/20/2018  06/20/2019  06/28/2019  06/28/2019  06/20/2018  06/20/2018  06/20/2018  06/20/2019  06/20/	Pending	METHOD AND SYSTEM FOR MOCVD			06/29/2018	10-2019-7020017	KR
06/24/2016 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS SURFACE PASSIVATION OF III-V OPTOELECTRONIC DEVICES 10/03/2019 CONTOELECTRONIC DEVICES MODULES INCORPORATING ENCAPSULATION LAYERS 05/14/2019 MIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS 09/10/2020 SYSTEMS AND METHODS FOR LARGE SCALE GAS GROUP THIN PHOTOVOLTAICS OFF METHOD AND SYSTEM FOR MOCVD EFFLUENT ABATEMENT 06/29/2018 METHOD AND SYSTEM FOR MOCVD EFFLUENT ABATEMENT 06/28/2019 METHOD AND SYSTEM FOR MOCVD EFFLUENT ABATEMENT  06/28/2019 METHOD AND SYSTEM FOR MOCVD EFFLUENT ABATEMENT		ETTLOEN I ABA I EIMEN I					
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06/24/2016 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS  SURFACE PASSIVATION OF III-V OPTOELECTRONIC DEVICES  10/03/2019 MODULES INCORPORATING ENCAPSULATION LAYERS O5/14/2019 HIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS O9/10/2020 SYSTEMS AND METHODS FOR LARGE SCALE GAS GENERATION EXTERNAL STRESS ASSISTED EPITAXIAL LIFT-OFF METHOD OF THIN PHOTOVOLTAICS  12/28/2020 METHOD AND SYSTEM FOR MOCVD EFFLUENT ABATEMENT  06/29/2018 METHOD AND SYSTEM FOR MOCVD EFFLUENT ABATEMENT  METHOD AND SYSTEM FOR MOCVD EFFLUENT ABATEMENT  METHOD AND SYSTEM FOR MOCVD  METHOD AND SYSTEM FOR MOCVD		EFFLUENT ABATEMENT					
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06/24/2016  06/24/2016  05/14/2019	renaing	GAS GENERATION			02/10/2020	63/0/6015	US
06/24/2016 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR  MANUFACTURE OF PHOTOVOLTAIC CELLS  SURFACE PASSIVATION OF III-V  OPTOELECTRONIC DEVICES  MODULES INCORPORATING  ENCAPSULATION LAYERS  05/14/2019 HIGH GROWTH RATE DEPOSITION FOR		GROUP III/V MATERIALS					
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06/24/2016 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS SURFACE PASSIVATION OF III-V OPTOELECTRONIC DEVICES 10/03/2019 MODULES INCORPORATING	·	ENCAPSULATION LAYERS			·	·	
06/24/2016 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS SURFACE PASSIVATION OF III-V OPTOELECTRONIC DEVICES	Pending	MODULES INCORPORATING			10/03/2019	16/592124	SN
06/24/2016 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS	Expired				05/14/2019	62/847766	SN
06/24/2016 3550597 01/20/2021 PRESSURIZED HEATED ROLLING PRESS FOR	***************************************	MANUFACTURE OF PHOTOVOLTAIC CELLS					
	Granted	PRESSURIZED H	01/20/2021	3550597	06/24/2016	19176210.3	EP

Granted	TAPE-BASED EPITAXIAL LIFT OFF APPARATUSES AND METHODS	05/29/2019	2359393	12/17/2009	09836939.0	GB
Granted	TAPE-BASED EPITAXIAL LIFT OFF APPARATUSES AND METHODS	05/29/2019	2359393	12/17/2009	09836939.0	NL
Granted	TAPE-BASED EPITAXIAL LIFT OFF APPARATUSES AND METHODS	05/29/2019	60 2009 058 579.7	12/17/2009	09836939.0	DE
Granted	TAPE-BASED EPITAXIAL LIFT OFF APPARATUSES AND METHODS	05/29/2019	2359393	12/17/2009	09836939.0	BE
Unfiled	HARVESTABLE INDOOR ENERGY METER					SN
	INTERCONNECTION FOR FLEXIBLE SOLAR MODULES					
Published	VERSATILE FLEXIBLE CIRCUIT			09/13/2019	16/570927	SN
	INTERCONNECTION FOR CONNECTING TWO FLEXIBLE SOLAR CELLS					
Published	VERSATILE FLEXIBLE CIRCUIT			09/13/2019	16/570882	SN
	JUNCTIONS					
	LATTICE-MATCHED DILUTE NITRIDE					
Pending	THIN-FILM, FLEXIBLE MULTI-JUNCTION			03/22/2019	2019-551316	JP
	JUNCTIONS					
	LATTICE-MATCHED DILUTE NITRIDE					
,	OPTOELECTRONIC DEVICES INCORPORATING					
Pending	THIN-FILM, FLEXIBLE MULTI-JUNCTION			03/22/2019	10-2019-7031712	KR
	JUNCTIONS					
	OPTOELECTRONIC DEVICES INCORPORATING					
Published	THIN-FILM, FLEXIBLE MULTI-JUNCTION			03/22/2019	201980001919.3	CN
	JUNCTIONS					
	LATTICE-MATCHED DILUTE NITRIDE					
	OPTOFI FOTRONIC DEVICES INCORPORATING			00/14/1010		ŗ
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	DEVICES INCORPORATING A SINGLE LATTICE-				•••••	
Pending	THIN-FILM, FLEXIBLE OPTOELECTRONIC			03/22/2019	2019-548307	JP
	METHODS					
	MATCHED DITTE NITRIDE ITINGTION AND					
Pending	THIN-FILM, FLEXIBLE OPTOELECTRONIC			03/22/2019	10-2019-7024287	Ŕ
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Granted	VIA STRUCTURES FOR SOLAR CELL INTERCONNECTION IN SOLAR MODULE	09/04/2019	3350843	09/16/2016	16770656.3	BE
Granted	VIA STRUCTURES FOR SOLAR CELL INTERCONNECTION IN SOLAR MODULE	09/04/2019	3350843	09/16/2016	16770656.3	Ę
Granted	VIA STRUCTURES FOR SOLAR CELL INTERCONNECTION IN SOLAR MODULE	09/04/2019	3350843	09/16/2016	16770656.3	GB
Granted	VIA STRUCTURES FOR SOLAR CELL INTERCONNECTION IN SOLAR MODULE	09/04/2019	602016020042.2	09/16/2016	16770656.3	DE
Published	DISTRIBUTION VALVE			07/30/2019	PCI/032019/044131	PC
Published	HARVESTABLE INDOOR ENERGY METER			07/30/2019	PCT/US2019/044122	PC
Published	HIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS			09/07/2018	18779506.7	EP
Pending	HIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS			09/07/2018	2019-541292	JP
Pending	HIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS			09/07/2018	10-2019-7022544	KR
Published	HIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS			09/07/2018	201880024678.X	CN
Granted	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS	07/24/2019	3314639	06/24/2016	16745889.2	GB
Granted	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS	07/24/2019	3314639	06/24/2016	16745889.2	NL
Granted	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS	07/24/2019	60 2016 017 405.7	06/24/2016	16745889.2	DE
Granted	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS	07/24/2019	3314639	06/24/2016	16745889.2	FR
Granted	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE OF PHOTOVOLTAIC CELLS	07/24/2019	3314639	06/24/2016	16745889.2	BE
Granted	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE AND METHOD OF USE	07/24/2019	3314640	06/24/2016	16741433.3	GB
Granted	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE AND METHOD OF USE	07/24/2019	3314640	06/24/2016	16741433.3	NL
Granted	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE AND METHOD OF USE	07/24/2019	60 2016 017 395.6	06/24/2016	16741433.3	DE
Granted	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE AND METHOD OF USE	07/24/2019	3314640	06/24/2016	16741433.3	FR
Granted	PRESSURIZED HEATED ROLLING PRESS FOR MANUFACTURE AND METHOD OF USE	07/24/2019	3314640	06/24/2016	16741433.3	BE

201880033436.7 06/15/2018   CROWTH STRUCTURE UNDER A RELEASE   10-2019-7035002 06/15/2018   CROWTH STRUCTURE UNDER A RELEASE   10-2019-7035002 06/15/2018   CROWTH STRUCTURE UNDER A RELEASE   2019-563844 06/15/2018   CROWTH STRUCTURE UNDER A RELEASE   2019-563845 09/27/2019   CROWTH STRUCTURE UNDER A RELEASE   2019-56385   2019-70212   201		DEVICES					
201880033436.7   06/15/2018   CHAPTER FOR MANUFACTURING OF LAYER FOR MANUFACTURING OF LOPTICE CTRONIC DEVICES GROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF LOPTICE CTRONIC DEVICES GROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF LAYER FOR MANUFACTURING SOLAR CELLS LISTANDA AND METHOD FOR INTERCONNECTING SOLAR			,,,,,,				
201880033436.7   06/15/2018   GROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF DPTOELECTRONIC DEVICES STATEMENT OF MODIFICATION OF PHOTOVOLTAICS OF DPTOELECTRONIC DEVICES INCLUDING OF DPTOELECTRONIC DEVICES INCLUDING OF DPTOELECTRONIC DEVICES INCLUDING DEVICES INCLUDIN	Published	SELF-BYPASS DIODE FUNCTION FOR			02/13/2020	PCT/US2020/018028	PC
201880033436.7   06/15/2018   GROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES CROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES CROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES CROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES CROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES CROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES CROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES CROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES CROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES CROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES (NCLUDING HETERQUINCTION OF PHOTOVOUTAICS OPTOELECTRONIC DEVICES (NCLUDING HETERQUINCTION OF PHOTOVOUTAICS OPTOELECTRONIC DEVICES (NCLUDING HETERQUINCTION OPTOELECTRONIC DEVICES (NCLUDING HETERQUINCTING SOLAR CELLS (N			,,,,,,				
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201880033436.7   06/15/2018   GROWTH STRUCTURE UNDER A RELEASE LAYER FOR MANUFACTURING OF OPTOELECTRONIC DEVICES	Granted	ERCONNECTING SOLAR	10/30/2019	3403283	01/12/2017	17702212.6	BE
201880033436.7   06/15/2018   GROWTH STRUCTURE UNDER A RELEASE		CELLS					
201880033436.7   06/15/2018   GROWTH STRUCTURE UNDER A RELEASE	Granted	INTERCO	10/30/2019	3403283	01/12/2017	17702212.6	GB
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201880033436.7 06/15/2018 GROWTH STRUCTURE UNDER A RELEASE 10-2019-7035002 06/15/2018 CAYER FOR MANUFACTURING OF 0PTOELECTRONIC DEVICES 2019-563844 06/15/2018 GROWTH STRUCTURE UNDER A RELEASE 2019-563844 06/15/2018 GROWTH STRUCTURE UNDER A RELEASE 18738110.8 06/15/2018 GROWTH STRUCTURE UNDER A RELEASE 18738110.8 06/15/2018 GROWTH STRUCTURE UNDER A RELEASE 18738110.8 06/15/2018 GROWTH STRUCTURE UNDER A RELEASE 16/585436 09/27/2019 GROWTH STRUCTURE UNDER A RELEASE 11/063357 10/05/2020 GROWTH STRUCTURING OF 0PTOELECTRONIC DEVICES 11/03/2011 2450956 09/04/2019 OPTOELECTRONIC DEVICES INCLUDING 11187659.5 11/03/2011 2450956 09/04/2019 OPTOELECTRONIC DEVICES INCLUDING		:	,,,,,,				
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	Published	GROWTH STRUCTURE UNDER A RELEASE			06/15/2018	201880033436.7	CN

Closed	NON-ANNEALED METAL CONTACT TO SEMICONDUCTOR MATERIAL					Sn
Closed	METAL CONTACT FORMATION AND WINDOW ETCH STOP FOR PHOTOVOLTAIC DEVICES					υs
Granted	SELF-BYPASS DIODE FUNCTION FOR GALLIUM ARSENIDE PHOTOVOLTAIC DEVICES	11/08/2017	2487712	02/09/2012	12154739.2	NL
Granted	SELF-BYPASS DIODE FUNCTION FOR GALLIUM ARSENIDE PHOTOVOLTAIC DEVICES	11/08/2017	60 2012 039 408.0	02/09/2012	12154739.2	DE
Granted	SELF-BYPASS DIODE FUNCTION FOR GALLIUM ARSENIDE PHOTOVOLTAIC DEVICES	11/08/2017	2487712	02/09/2012	12154739.2	BE
Closed	VIA STRUCTURES FOR SOLAR CELL INTERCONNECTION IN SOLAR MODULE					Sn
Published	SURFACE PASSIVATION OF III-V OPTOELECTRONIC DEVICES			05/13/2020	15/931513	Sn
Published	SURFACE PASSIVATION OF III-V OPTOELECTRONIC DEVICES			05/14/2020	PCT/US2020/032854	PC
Published	HIGH GROWTH RATE DEPOSITION FOR GROUP III/V MATERIALS			05/13/2020	PCT/US2020/032676	PC
Published	METHODS AND SYSTEMS FOR CLEANING DEPOSITION SYSTEMS			04/30/2020	PCT/US2020/030764	PC
Published	SPUTTERED THEN EVAPORATED BACK METAL PROCESS FOR INCREASED THROUGHPUT			04/30/2020	PCT/US2020/030683	PC
Published	LASER-TEXTURED THIN-FILM SEMICONDUCTORS BY MELTING AND ABLATION			03/19/2020	PCT/US2020/023510	PC
Published	FRONT METAL CONTACT STACK			03/19/2020	PCT/US2020/023501	PC
Published	METHOD AND SYSTEMS FOR ALIGNMENT TO EMBEDDED PATTERNS IN SEMICONDUCTOR DEVICE PROCESSING			03/06/2020	PCT/US2020/021356	PC
Published	METHODS AND SYSTEMS FOR ALIGNMENT TO EMBEDDED PATTERNS IN SEMICONDUCTOR DEVICE PROCESSING			03/05/2020	16/809911	Sn

	ENCAPSULATION LAYERS				
Pending	MODULES INCORPORATING		10/02/2020	PCT/US2020/054010	PC
	CONDENSATION REGION				
Pending	GAS TRAP SYSTEN				PC
	FEATURES				
Pending	ING 	,,,,,,	10/14/2020	PCT/US2020/055624	PC
	DIFFERENT GROWTH SUBSTRATES				
•••••	OPTOELECTRONIC DEVICES USING				
Pending	METHODS OF MANUFACTURING Pending		10/16/2020	PCT/US2020/056122	PC
	USING DIFFERENT GROWTH SUBSTRATES				
Pending	OPTOELECTRONIC DEVICES MANUFACTURED		10/16/2020		PC
	MULTI-POINT PROBE				
	MATERIAL USING A NON-DESTRUCTIVE				
	ELECTRICAL CHARACTERISTICS OF A				
Published	SYSTEMS AND METHODS FOR MEASURING		07/02/2020	PCT/US2020/040781	PC
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**RECORDED: 05/03/2021**